

<p><b>IDS - 05/11/2006</b></p> <p><b>INFORMATION DISCLOSURE CITATION</b></p> <p><i>(Use several sheets if necessary)</i></p>	<p><b>Docket number (Optional)</b></p> <p><b>15689.49.4</b></p>	<p><b>Application Number</b></p> <p><b>10/673,940</b></p>
<p><b>Applicant(s)</b></p> <p><b>Takehiro Nakamura et al.</b></p>		
<p><b>Filing Date</b></p> <p><b>September 29, 2003</b></p>		
<p><b>Group Art Unit</b></p> <p><b>2611</b></p>		

**U.S. PATENT APPLICATION PUBLICATIONS**

## **FOREIGN PATENT DOCUMENTS**

**EXAMINER** /Kevin Kim/ (09/30/2006)

**DATE CONSIDERED**

**EXAMINER:** Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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